

GAS HANDLING EQUIPMENT

GLASS VARIABLE AREA FLOWMETER



HSG-GTV

HSG GTV Series glass variable area flowmeter consists of a glass flow tube and float scaled to the flow units required, and a frame to provide the end block supports and to cover and protect the tube. HSG-GTV is ideal for panel mounting, they are supplied with mounting studs and a rear facing exhaust vent to safely exhaust process gas should a tube fail. Models can have rear facing or in-line process connections and the GTV/B units have a built in needle valve for flow control. Float and scale visibility is improved through the use of a clear polycarbonate cover set against a white background.

Series HSG-GTV Flowmeters Features

- Easy to use, high visibility scale
- Simple and reliable
- Gas flow measurement
- Operator confidence from float rotation
- Instantaneous response
- Accuracy up to $\pm 1.25\%$ FSD
- Air flow range 5 cm³/min to 150 L/min
- Linear scales, typically 10:1 range
- Glass tube removal without tools
- Option of integral needle valve
- Special scales available on request

Available Ranges

Flow Rate (Air @ ATP)

5 - 100 cm ³ /min
20 - 250 cm ³ /min
60 - 600 cm ³ /min
0.1 - 1.2 L/min
0.2 - 2.0 L/min
0.2 - 3.4 L/min
0.6 - 5.0 L/min
1 - 10 L/min
1 - 12 L/min
2 - 25 L/min
6 - 50 L/min
10 - 100 L/min
30 - 150 L/min

MEMBRANE LINE FILTER



HSG-GF500

The HSG-GF500 Teflon® Membrane Line Filter efficiently traps particles down to 0.01 microns. These units may be installed in gas lines supplied by cylinders or bulk sources. Both the materials and manner of construction allow the HSG-GF500 to be compatible with a wide variety of gases.

Series HSG-GF500 Membrane Line Filter Features

- 100% efficient at 0.01 micron level
- Filter medium-porous PTFE Teflon® membrane
- All welded 316L stainless steel construction
- Internal finish - less than 15Ra
- 0.05 sq. ft. filter area provides high particle retention capacity
- Excellent compatibility with a wide variety of gases

Typical Applications

- Gas chromatography
- Pharmaceutical manufacturing
- Pneumatic operated devices
- Semiconductor manufacturing

Specifications

Filtration	100% @ 0.01 microns
Max. operating pressure	1000 psig @ 70°F
Max. operating temperature	100°F